Special Issue

Design and Fabrication of Micro/Nano Sensors and Actuators

Message from the Guest Editors

With the rapid development of materials science and manufacturing technology, numerous novel MEMS and NEMS devices, such as micro/nano sensors, micro/nano actuators and flexible sensors, have emerged in many application fields. These above devices are always made of silicon, metals, ceramics, glass, and so on, whose mechanical and electrical properties have great influence on their working characteristics, including accuracy, sensitivity and working range. In addition, the design and fabrication method can directly affect the reliability of those MEMS and NEMS devices, especially lifetime, robustness and stability under extreme conditions of shock, temperature, humidity, irradiation, chemical exposure, or other challenges. Accordingly, this Special Issue seeks to showcase research papers and review articles that focus on design and fabrication of micro/nano sensors, actuators and flexible sensors. Areas of interest include but are not limited to:

- Structural design and optimization methods;
- System modeling and simulation;
- Advanced fabrication techniques;
- In situ characterization and testing technology;
- Reliability of devices and systems.

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Deadline for manuscript submissions

closed (15 April 2022)

Micromachines

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Impact Factor 3.0
CiteScore 6.0
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